

## Mechanisms of Diffusion of Boron Impurities in SiO<sub>2</sub>

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We report first-principle total-energy calculations that clarify mechanisms of boron diffusion in SiO<sub>2</sub>. We find that a B atom takes a variety of stable and metastable geometries depending on its charge state. We also find that atomic rearrangements during the diffusion manifest a wealth of bonding feasibility in SiO<sub>2</sub> and that the calculated activation energy agrees with the experimental data available. Recombination enhanced diffusion is also proposed.

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Atomic diffusion constitutes fundamental phenomena in materials [1,2]. In semiconductors, for instance, placement of dopant atoms in required regions through diffusion is essential to realize designed performances of devices. Hence a large number of efforts have been made to clarify mechanisms of the atomic diffusion in semiconductors, mainly in Si [3–8].

Semiconductor devices do not consist solely of semiconductors, however. It has been said that were it not for its oxide, Si would lose its premier status in technology: The oxide SiO<sub>2</sub> formed with relative ease insulates Si from the metallic electrode and hereby ensures functions of electronic devices. Yet the guarantee provided by SiO<sub>2</sub> is threatened in current nanometer-scale miniaturization: Leakage current through very thin SiO<sub>2</sub> films has been reported [9,10] and the possible reasons are examined [11,12]; moreover, diffusion of dopant atoms from electrodes, which are usually highly doped polycrystalline Si, and even their penetration through SiO<sub>2</sub> films have become serious [13]. It is thus urgent to clarify atom-scale mechanisms of the dopant diffusion in SiO<sub>2</sub>.

SiO<sub>2</sub> is an ambivalent material, both covalent and ionic: A Si atom is coordinated with four oxygen atoms with  $sp^3$  hybridization, whereas the O atom substantially attracts electrons from nearby Si atoms. Although SiO<sub>2</sub> exhibits a variety of polymorphs, this situation is common even in amorphous SiO<sub>2</sub>. Diffusion is the sequence of cooperative atomic reactions in which covalent bonds are rearranged as a diffusing species migrates. The probable rearrangements are determined by total-energy surfaces that may be sensitive to the local charge distribution around the diffusing species. Diffusion of a foreign atom in ambivalent SiO<sub>2</sub>, which has not been focused in the past [14,15], is therefore of interest also from scientific viewpoints.

In this Letter, we have performed total-energy calculations to clarify mechanisms of B diffusion in SiO<sub>2</sub>. We have found that the B impurity has a variety of stable and metastable atomic geometries depending on its charge state, exhibiting negative-U characters. Diffusion pathways from those stable geometries and corresponding activation energies are also found to be sensitive to the

charge state. Detailed examination of atomic geometries during the diffusion unravels surprisingly rich chemical feasibility of the constituent elements. The calculated activation energies agree with experimental data.

The density-functional theory is used within the generalized-gradient approximation [16–18]. Norm-conserving pseudopotentials for Si [19] and ultrasoft pseudopotentials for O and B [20] are adopted to describe the electron-ion interaction. As a representative of SiO<sub>2</sub>, we consider  $\alpha$ -quartz [21]. The supercell containing 72 lattice sites is used to simulate a B impurity in an otherwise perfect SiO<sub>2</sub>. The cutoff energy of the plane-wave basis set is 25 Ry. We use the  $\Gamma$  point for the Brillouin zone (BZ) sampling [22]. Geometries are optimized for all atoms until the remaining force on each atom is less than 5 mRy/Å. The diffusion pathways and activation energies for the B impurity are calculated by the constrained optimization in a  $(N - 1)$ -dimensional space [23], where  $N$  is the ionic degrees of freedom in a unit cell. For the charged states, a monopole model [12] is used to correct the total-energy lowering due to spurious Coulomb interactions in the supercell model.

We have performed an extensive search for stable geometries of B in SiO<sub>2</sub> and found charge-state dependent multistability. Figure 1 shows stable and metastable geometries of B in SiO<sub>2</sub>. In the most stable geometry B<sub>S</sub>Si<sub>(3)</sub> [Fig. 1(a)] with the neutral charge state, B and Si atoms take a split-interstitial configuration around the original Si site and, surprisingly, the Si atom becomes threefold coordinated. We have also found other metastable geometries B<sub>ox</sub> [Fig. 1(b)], B<sub>O</sub>Si<sub>(5)</sub> [Fig. 1(c)], and B<sub>O</sub>O<sub>i</sub> [Fig. 1(d)]. In B<sub>ox</sub>, which is higher than B<sub>S</sub>Si<sub>(3)</sub> in total energy by 0.09 eV, a B atom intervenes between Si and O atoms and is twofold coordinated. When the B and the neighboring O are exchanged in B<sub>ox</sub>, we reach another metastable geometry B'<sub>ox</sub>, higher than B<sub>ox</sub> in energy by 0.24 eV. In B<sub>O</sub>Si<sub>(5)</sub>, which is higher than B<sub>S</sub>Si<sub>(3)</sub> in energy by 0.21 eV, a B atom substitutes for an O atom, the dislodged O atom forms a weak bond with another Si atom, and this Si becomes fivefold coordinated (floating bond [24]). Another floating bond configuration B<sub>O</sub>O<sub>i</sub> in which B and the dislodged O are bonded to the Si and

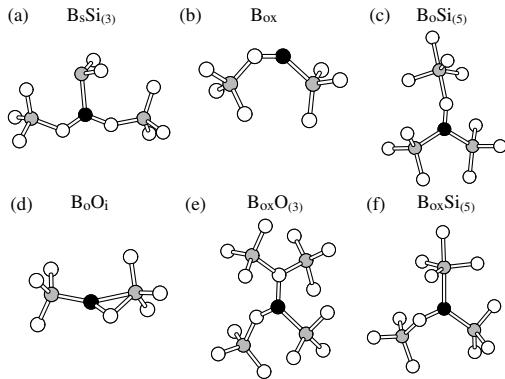


FIG. 1. Stable and metastable atomic geometries of a B impurity in SiO<sub>2</sub>. The B<sub>S</sub>Si<sub>(3)</sub> (a), B<sub>ox</sub> (b), B<sub>0</sub>Si<sub>(5)</sub> (c), B<sub>0</sub>O<sub>i</sub> (d), B<sub>ox</sub>O<sub>(3)</sub> (e), and B<sub>ox</sub>Si<sub>(5)</sub> (f) geometries. White, gray, and black balls indicate O, Si, and B atoms, respectively. Only a part of the atoms in a unit cell are shown to avoid visual complexity.

thereby form a floating bond is also found to be metastable but 0.53 eV higher in energy than B<sub>S</sub>Si<sub>(3)</sub>. Obtained stability of B<sub>S</sub>Si<sub>(3)</sub> is interpreted in terms of bond strength: In B<sub>S</sub>Si<sub>(3)</sub> there is a Si dangling bond, whereas in B<sub>ox</sub> a B dangling bond; the total-energy difference of 0.09 eV between B<sub>S</sub>Si<sub>(3)</sub> and B<sub>ox</sub> is comparable with the bond energy difference,  $\epsilon_{\text{Si-O}} = 8.29$  eV and  $\epsilon_{\text{B-O}} = 8.38$  eV [25].

Analyses of Kohn-Sham levels clarify that a deep level appears in the gap for each of the (meta)stable geometries with the neutral charge state. An electron is accommodated in the deep level so that the spin is 1/2. Yet the characters are different from each other: the Si dangling bond in B<sub>S</sub>Si<sub>(3)</sub>, the B dangling bond in B<sub>ox</sub>, and the antibonding character between the O-nonbonding and the B-Si bonding states in B<sub>0</sub>Si<sub>(5)</sub>.

Energetics depends on the charge state. For positively charged (+1) state, B<sub>0</sub>Si<sub>(5)</sub> and B<sub>0</sub>O<sub>i</sub> geometries become unstable. The most stable geometry is B<sub>ox</sub>O<sub>(3)</sub> in Fig. 1(e) in which a B atom intervenes between Si and O atoms, and then forms the third bond with the nearby O atom. A missing electron in the +1 state causes two electrons of the nonbonding state of the nearby O to assist in the formation of the third bond with B. B<sub>ox</sub> and B<sub>S</sub>Si<sub>(3)</sub> geometries are found to be metastable and are higher than B<sub>ox</sub>O<sub>(3)</sub> in total energy by 0.74 and 0.50 eV, respectively. For the negatively charged (−1) state, the B<sub>ox</sub> and B<sub>ox</sub>O<sub>(3)</sub> become unstable. We have found that B<sub>0</sub>Si<sub>(5)</sub> geometry in Fig. 1(c) is the most stable geometry. An additional electron is effective to strengthen the floating bond around Si and stabilizes B<sub>0</sub>Si<sub>(5)</sub>. As a metastable geometry we have found B<sub>S</sub>Si<sub>(3)</sub> and B<sub>ox</sub>Si<sub>(5)</sub> [Fig. 1(f)] which are higher than B<sub>0</sub>Si<sub>(5)</sub> in total energy by 0.77 and 1.32 eV, respectively.

In the neutral state, there are several metastable geometries of which energies are close to that of the most

stable. In negatively or positively charged states, on the other hand, the energy of the most stable geometry is substantially lower than those of other metastable geometries. This is owing to a fact that the missing or the additional electron is effective in forming the peculiar bond configuration in each charged state. This charge-state-dependent chemical feasibility has important consequences in the B diffusion explained below.

The stability among different charge states in their equilibria is obtained by comparing  $\Omega(Q, \mu) \equiv E(Q) + Q\mu$ , where  $E(Q)$  is the total energy of the charge state  $Q$ , and  $\mu$  is the electron chemical potential, i.e., the Fermi level in the energy gap. Figure 2 shows  $\Omega(Q, \mu)$  for some of the (meta)stable geometries of the B impurity explained above as a function of  $\mu$  for the positive (+1;  $Q = 1$ ), neutral (0;  $Q = 0$ ), and negative (−1;  $Q = -1$ ) charge states. The  $\mu$  value  $\mu_{\text{th}}(Q/Q + 1)$ , at which  $\Omega(Q, \mu) = \Omega(Q + 1, \mu)$ , determines the relative stability of the  $Q$  and  $(Q + 1)$  charge states and is called the thermodynamic level [12]. Figure 2 clearly shows that positively charged or negatively charged states are stable, whereas the neutral charge state is metastable for any value of  $\mu$  in the energy gap. Hence the B in SiO<sub>2</sub> is a

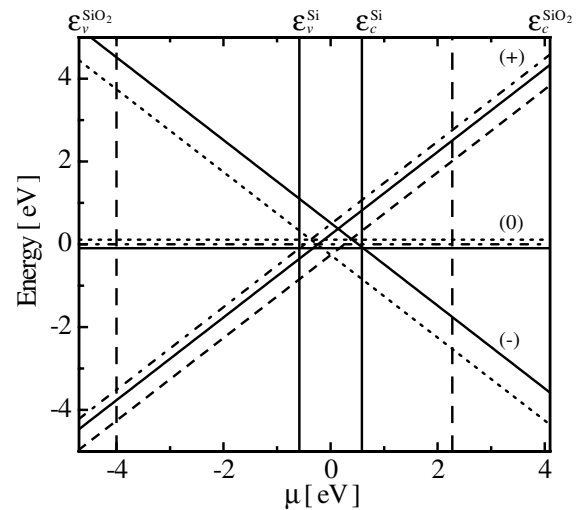


FIG. 2. Relative formation energies  $\Omega(Q, \mu)$  of several stable geometries of the B impurity as a function of the electron chemical potential  $\mu$  in the energy gap of SiO<sub>2</sub>: B<sub>S</sub>Si<sub>(3)</sub> (solid lines), B<sub>0</sub>Si<sub>(5)</sub> (dotted lines), B<sub>ox</sub> (dash-dotted lines), and B<sub>ox</sub>O<sub>(3)</sub> (dashed lines). The energies for the positive (+), neutral (0), and negative (−) charge states are shown. Both ends of  $\mu$  are the experimental valence band top ( $\epsilon_v^{\text{SiO}_2}$ ) and conduction band bottom ( $\epsilon_c^{\text{SiO}_2}$ ) of SiO<sub>2</sub>. Those of Si ( $\epsilon_v^{\text{Si}}$  and  $\epsilon_c^{\text{Si}}$ ) are denoted by vertical lines. The density-functional  $\epsilon_v^{\text{SiO}_2}$  and  $\epsilon_c^{\text{SiO}_2}$  are shown as a reference by vertical dashed lines near both ends of  $\mu$ . These alignments are done by matching the theoretical and experimental thermodynamic levels [26] related to the interstitial H in SiO<sub>2</sub>, which is known to be located at 0.2 eV above the center of the Si gap (the energy reference here), and by using the valence-band offset of 4.3 eV between SiO<sub>2</sub> and Si (refer to [12] for details).

negative-U system associated with structural transformation. The energy cost to render the charged states neutral is found to be 0.2–0.8 eV when  $\mu$  is in the region of the Si energy gap.

We are now in a position to discuss the diffusion. We start with the most stable geometry and explore a variety of possible diffusion pathways toward the final geometry [27] using our constrained minimization technique. The most favorable pathways and corresponding activation energies determined by the present calculations are shown in Fig. 3. We have found that the B atom diffuses along bond networks of SiO<sub>2</sub> irrespective of its charge state, deforming and breaking a bond configuration, and then forming a next favorable bond configuration. In the +1 state, starting from B<sub>ox</sub>O<sub>(3)</sub>, the B takes the metastable geometry of B'<sub>ox</sub>, diffuses through the saddle point (see below) towards another metastable B<sub>ox</sub>, breaks and reforms several configurations, and then diffuses to the final B<sub>ox</sub>O<sub>(3)</sub> geometry again through the B'<sub>ox</sub>. In the -1 state, the B starts from the initial B<sub>O</sub>Si<sub>(5)</sub>, passes through the saddle point (see below), and reaches the nearby B<sub>O</sub>Si<sub>(5)</sub>. Yet this B<sub>O</sub>Si<sub>(5)</sub> is still the halfway point. To proceed farther from the initial B<sub>O</sub>Si<sub>(5)</sub>, the B takes another metastable B<sub>ox</sub>Si<sub>(5)</sub> and then reaches the final geometry. When the B is in the neutral state, rearrangements of several bonding configurations are again required to reach the final geometry. Yet activation energy for the diffusion of neutral B is substantially lower than those for charged B: The calculated barriers for the

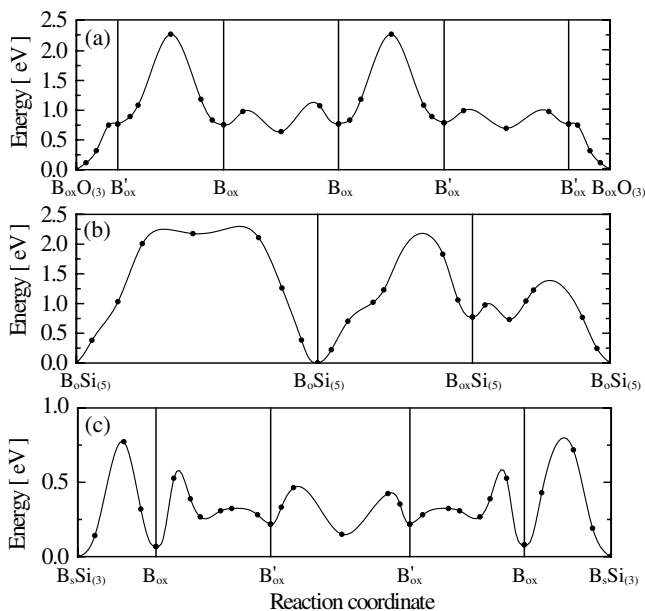


FIG. 3. Total energy variations along diffusion pathways: the B<sub>ox</sub>O<sub>(3)</sub> → B<sub>ox</sub>O<sub>(3)</sub> path with positively charged (a), the B<sub>O</sub>Si<sub>(5)</sub> → B<sub>O</sub>Si<sub>(5)</sub> path with negatively charged (b), and the B<sub>S</sub>Si<sub>(3)</sub> → B<sub>S</sub>Si<sub>(3)</sub> path with neutral (c) states. The left and right ends correspond to the initial and the final geometries. The vertical lines denote intermediate metastable geometries.

neutral B is 0.8 eV, whereas those for the +1 and the -1 states are 2.3 and 2.2 eV, respectively. This is due to the charge-state-dependent chemical feasibility stated above.

Variation of atomic geometries during the diffusion is extremely interesting and further elucidates the importance of the charge state. The saddle point for the +1 state lies between the B<sub>ox</sub> and the B'<sub>ox</sub> geometries and is shown in Fig. 4(a). The barrier determining process for the +1 state is the exchange process between B and O atoms, and this process, as is evident from Fig. 4(a), costs substantial energy. The saddle point for the -1 state is shown in Fig. 4(b) where the Si atoms around B form several floating bonds. It is found that an additional electron is shared consecutively by various floating bonds during the diffusion (not shown here). However, the total energy of the saddle-point geometry is much higher than the most stable B<sub>O</sub>Si<sub>(5)</sub>.

In the neutral state, the B diffusion requires the same structural transformation between B<sub>ox</sub> and B'<sub>ox</sub> as in the +1 state (Fig. 3). Yet the barrier is dramatically low, more than 1.5 eV lower than for the +1 state. Figure 4(c) clarifies the origin. For the neutral state, multiple bonds among B, O, and Si atoms are formed in the saddle-point geometry. This multiple-bond configuration in the neutral state is close to the metastable geometry B<sub>O</sub>O<sub>i</sub> [Fig. 1(d)] which is unstable for the +1 state. An electron which triggers the diffusion reaction toward the favorable saddle point in the neutral state is missing in the +1 state.

Our calculations indicate that the +1 or -1 charged state is more stable than the neutral state for any position of  $\mu$  in the gap (Fig. 2). It is thus concluded that the diffusion barrier is 2.2–2.3 eV in usual situations. This theoretical value agrees well with the experimental values [28].

In nonequilibrium conditions, however, we expect recombination enhanced diffusion. When  $\mu$  is in the region of Si energy gap, the total-energy difference between neutral and charged states is less than 1 eV. Starting from the +1 charged B<sub>ox</sub>O<sub>(3)</sub><sup>+</sup> geometry, for instance, the B atom becomes B'<sub>ox</sub><sup>+</sup> geometry. We have determined

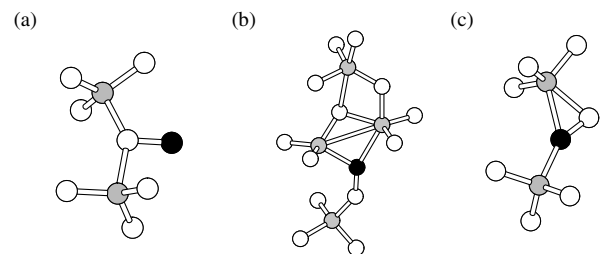


FIG. 4. Saddle-point geometries during the B diffusion for the +1 charged state (a) and the -1 charged state (b). A saddle-point geometry between B<sub>ox</sub> and B'<sub>ox</sub> for the neutral state is also shown in (c). White, gray, and black balls indicate O, Si, and B atoms, respectively. Only a part of atoms in a unit cell are shown to avoid visual complexity.

the reaction pathway  $B_{\text{ox}}O_{(3)}^{+1} \rightarrow B_{\text{ox}}'^{+1}$  and obtained the energy barrier of 0.8 eV. Upon electron capture at the  $B_{\text{ox}}'^{+1}$  geometry (intuitively, capture at the B dangling bond),  $B_{\text{ox}}'^{+1}$  becomes neutral  $B_{\text{ox}}'$  and migrates with the energy barrier of 0.5 eV [Figs. 3(a) and 3(c)]. The neutral  $B_{\text{ox}}'$  can be positive upon hole capture at some point and becomes the +1 charged  $B_{\text{ox}}'^{+1}$  and then  $B_{\text{ox}}O_{(3)}^{+1}$ . The net activation energy involves the energy gain to capture an electron at the geometry  $B_{\text{ox}}'$ . It is 0.0–0.5 eV from Fig. 2. Then the diffusion barrier for this whole recombination process is 0.8–1.3 eV. Similarly, for the negatively charged state the reaction,  $B_{\text{O}}Si_{(5)}^{-1} \rightarrow B_{\text{S}}Si_{(3)}^{-1} \rightarrow B_{\text{S}}Si_{(3)}^0 \cdots B_{\text{S}}Si_{(3)}^0 \rightarrow B_{\text{S}}Si_{(3)}^{-1} \rightarrow B_{\text{O}}Si_{(5)}^{-1}$ , substantially enhances the diffusion. We have obtained the energy barrier of 1.0–1.6 eV for this reaction.

In summary, we have presented first-principle calculations that clarify mechanisms of the B diffusion in  $\text{SiO}_2$ . The results clearly show characteristic features of the diffusion of a foreign atom in the ambivalent material which is both covalent and ionic. The charge-state-dependent feasibility of bond formations is the principal factor of the atomic diffusion.

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